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# United States Patent [19]

Chikaki et al.

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## [54] LAMINATING APPARATUS

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### Related U.S. Application Data

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[58] Field of Search ..... **156/285, 286,**  
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### [57]

### ABSTRACT

According to the present invention, there is proposed a laminating apparatus for laminating materials to be laminated. The apparatus includes at least one laminating section (9). Each laminating section (9) comprises an upper chamber (5) and an under chamber (6) wherein both chambers are divided with a diaphragm means (4). The apparatus further includes a heating stage (10) for heating the materials put on the stage in the under chamber (6). The stage (10) is movable between an upward position and a downward position. Further the apparatus includes a supporting means (13) which can support the materials in a position above and apart from the upper surface of the stage (10) when the stage locates in its downward position.

**12 Claims, 13 Drawing Sheets**

